

INFORMATION DISCLOSURE STATEMENT		Atty. Docket No.: 150.01010101		Serial No.: 09/388,286			
		Applicant(s): Guy T. Blalock					
		Filing Date: September 1, 1999		Group: Unknown			
U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	SubClass	Filing Date If Appropriate
AS		5,857,250	01/12/99	Riley et al.			
AS		5,906,726	05/25/99	Schneider et al.			
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	SubClass	Translation
							Yes No
		NONE					
OTHER DOCUMENTS (Including Authors, Title, Date, Pertinent Papers, etc.)							
AS		Kawahara et al., "(Ba, Sr)TiO ₃ Films Prepared by Liquid Source Chemical Vapor Deposition on Ru Electrodes," <i>Jpn. J. Appl. Phys.</i> , 35, Part 1, No. 9B, pp. 4880-4885 (September 1996).					
EXAMINER Anlu Soderquist				Date Considered 6/26/01			
*Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							